L Number	Hits	Search Text	DB	Time stamp
1	2376	thermoplastic near10 particulate	USPAT:	2004/01/25 21:33
,		•	US-PGPUB	
2	229	thermoplastic near10 (particulate powder)	USPAT;	2004/01/25 22:09
		near10 (sinter sintered sintering)	US-PGPUB	
3	35	tool near10 semiconductor near10 ceramic	USPAT;	2004/01/25 23:05
			US-PGPUB	
6	112	wire adj bonding adj capillary	USPAT;	2004/01/25 23:06
			US-PGPUB	, , , , , , , , , , , , , , , , , , , ,
7	5	(wire adj bonding adj capillary) same	USPAT;	2004/01/25 23:23
	1	ceramic	US-PGPUB	
-	2784	((wire adj bonding adj capillary) same	USPAT;	2004/01/25 23:10
		ceramic) same (diameter radius)	US-PGPUB	
-	2784	((wire adj bonding adj capillary) same	USPAT;	2004/01/25 23:10
		ceramic) and (diameter radius)	US-PGPUB	
10	112	(wire adj bonding adj capillary)	USPAT;	2004/01/25 23:30
			US-PGPUB	
11	0	((wire adj bonding adj capillary)) near10	USPAT;	2004/01/25 23:24
		micron	US-PGPUB	
13	` 4	((wire adj bonding adj capillary)) near10	USPAT;	2004/01/25 23:25
		ceraMIC	US-PGPUB	
14	32	(wire adj bonding adj capillary)	EPO; JPO;	2004/01/25 23:42
			DERWENT;	
			IBM TDB	
new .	6886	semiconductor near10 tool near10 (hole	USPAT;	2004/01/25 23:41
		borehole)	US-PGPUB	
_	6886	(semiconductor adj tool) near10 (hole	USPAT;	2004/01/25 23:41
		borehole)	US-PGPUB	
-	6886	(semiconductor adj tool) near5 (hole	USPAT;	2004/01/25 23:41
		borehole)	US-PGPUB	
-	219322	(semiconductor adj tool)	USPAT;	2004/01/25 23:42
	1		US-PGPUB	
-	219322	semiconductor adj tool	USPAT;	2004/01/25 23:42
		·	US-PGPUB	
_	219322	semiconductor adj tool	USPAT;	2004/01/25 23:43
			US-PGPUB	